Docket No.: 8733.1014.00-US

App No.: Not Yet Assigned Docket No.: 8733.1014.0
Inventor: Oh-Nam Kwon
Title: MANUFACTURING METHOD OF ELECTRO LINE FOR

SEMICONDUCTOR DEVICE

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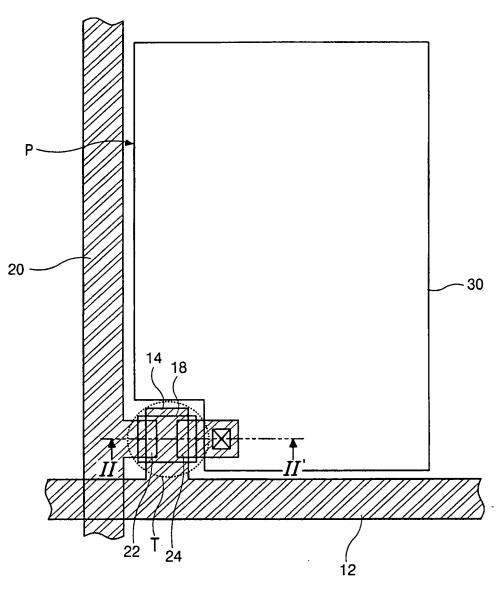


FIG. 1A **RELATED ART** 

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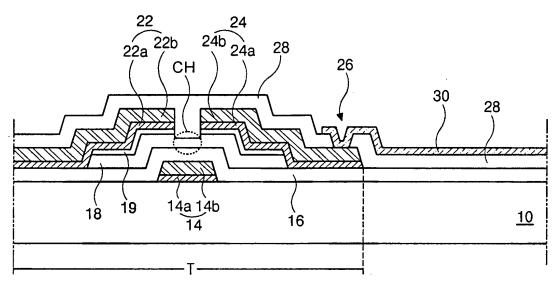


FIG. 1B RELATED ART

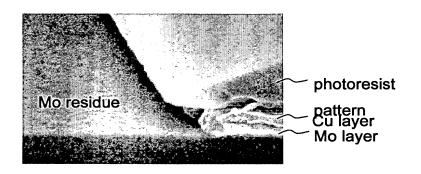


FIG. 2A RELATED ART

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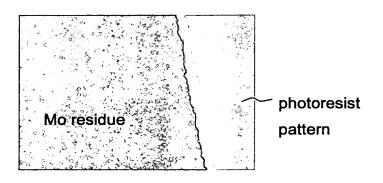


FIG. 2B RELATED ART

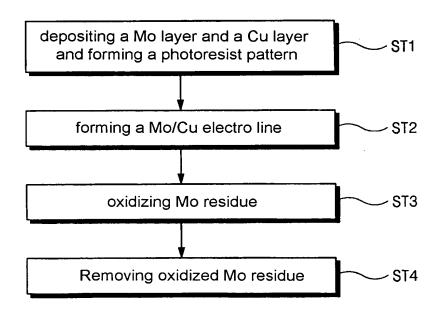


FIG. 3

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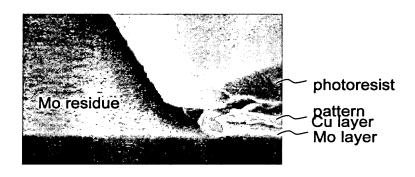


FIG. 4A

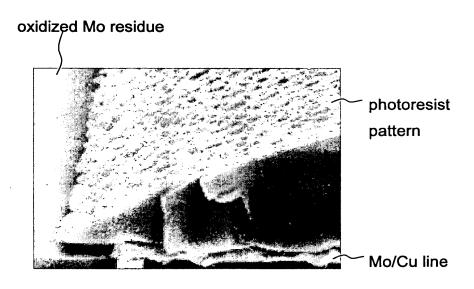


FIG. 4B

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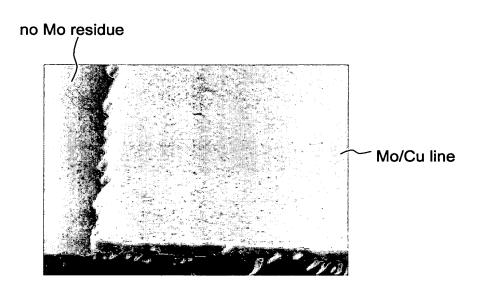


FIG. 4C

Docket No.: 8733.1014.00-US App No.: Not Yet Assigned Inventor: Oh-Nam Kwon Title: MANUFACTURING METHOD OF ELECTRO LINE FOR **PATENT** SEMICONDUCTOR DEVICE 8733.1014.00-US Sheet 6 of 6 forming a gate line and a gate electrode of Mo/Cu **ST11** (including a process of removing Mo residue) forming a gate insulating layer **ST12** and a semicondutor layer forming a data line, a source electrode **ST13** and a drain electrode forming a passivation layer ST14 having a drain contact hole forming a pixel electrode **ST15** 

FIG. 5